



LEPP REU

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SHEMELIN

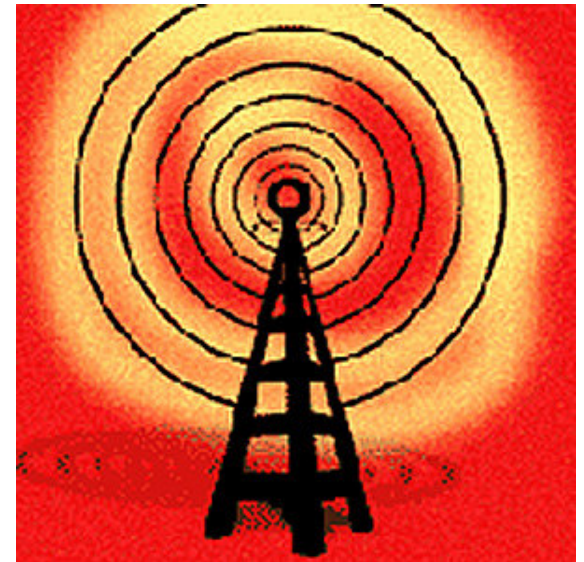
# Summer Goals

- GAIN VALUABLE RESEARCH EXPERIENCE
- CONTRIBUTE PRODUCTIVELY TO RESEARCH AT CORNELL

RESEARCH PROJECT PROVIDES  
OPPORTUNITY TO COMPLETE  
BOTH!!

## PROJECT:

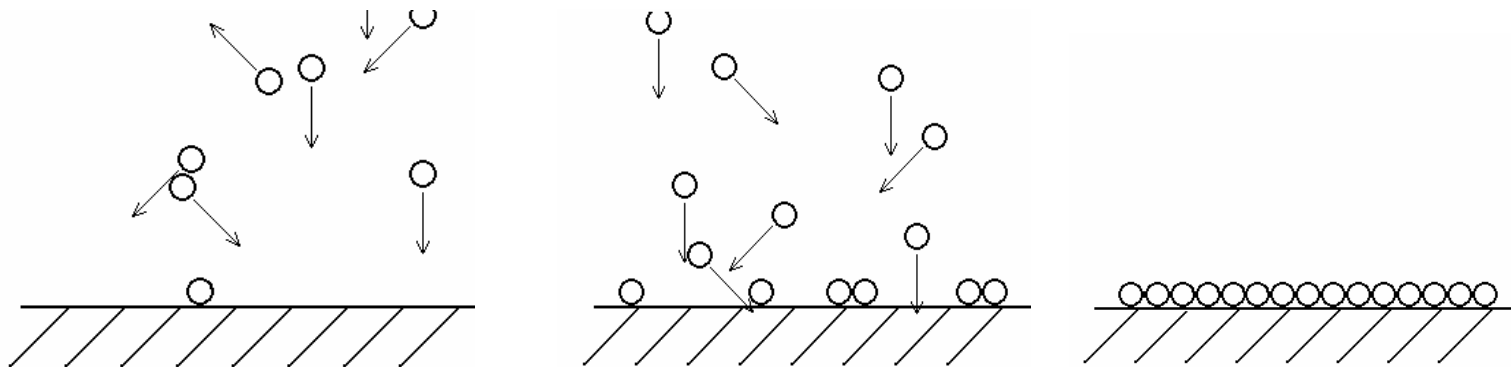
EVALUATE RF PROPERTIES OF  
NEG COATINGS AT FREQUENCIES  
UP TO 40 GHz



# NEG (Non-Evaporable Getter)

- NEG PUMPS ARE CAPTURE PUMPS
- BIND GAS MOLECULES CHEMICALLY TO SURFACE
- ONCE MONOLAYER SATURATES NEG SURFACE, MUST ACTIVATE THE NEG
- ORDER OF MICRONS IN THICKNESS (THIN-FILMS)

*NEG Coating*



# NEG in Lab

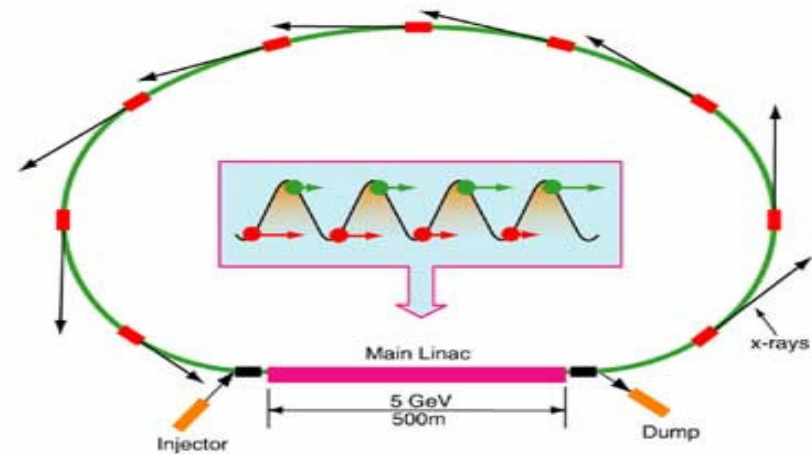
- VACUUM BENEFITS WELL KNOWN
- IMPEDANCE WITH RF IS NOT WELL KNOWN
- NEG'S CAN BE USED IN UNCONVENTIONAL PLACES
- ALSO PREVENT BUILD UP OF ELECTRON CLOUDS
- MUST UNDERSTAND NEG PROPERTIES IN RF TO UTILIZE IN ERL PROJECT

Low SEY  $\approx 1.1 \sim 1.4$

Low Outgassing

- Thermal
- Beam Induced (PID, EID, IID)

Distributed Pumping  $\rightarrow \frac{1}{S_{eff}} = \frac{1}{C} + \frac{1}{S}$



# Research

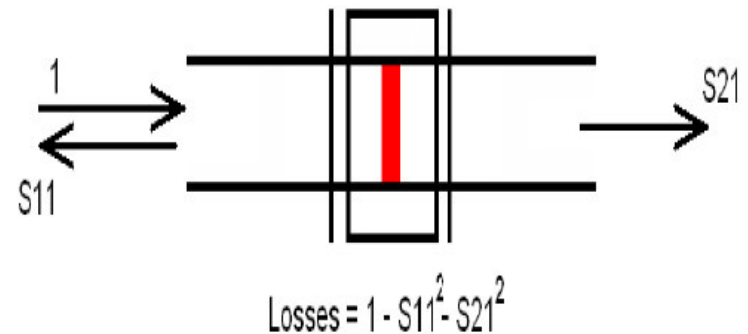
- STUDY TRANSMISSION AND REFLECTION OF NEG COATED MATERIALS
- RF WAVEGUIDES
- ORIGINAL PLAN REQUIRES MORE SENSITIVE EQUIPMENT
- IDEA: DESIGN NEW WAVEGUIDES THAT CAN BE COATED FOR EXPERIMENTS



INCREASE SENSITIVITY

Frequency:  
12.4 – 18 GHz

Dimensions:  
620 x 310 mils



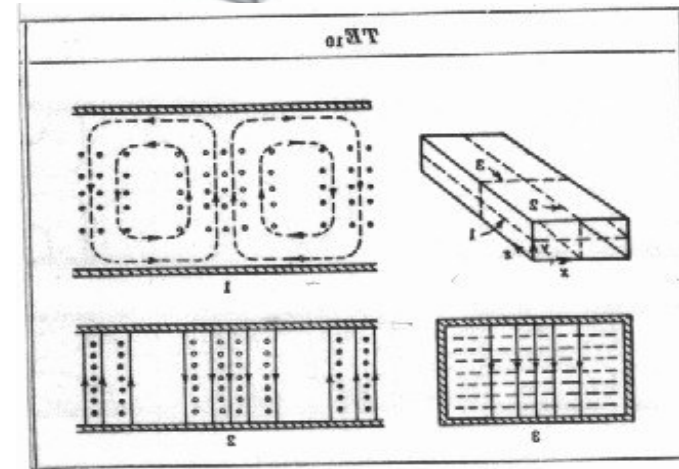
# Design

- MUST DESIGN WAVEGUIDE THAT CAN BE SUCCESSFULLY COATED AND TESTED IN THE LAB
- U-CHANNEL DESIGN LEAVES MAGNETIC FIELDS INSIDE WAVEGUIDE UNAFFECTED
- FIRMLY ATTACH NEG COATED FLAT SIDE TO U-CHANNEL
- CAN NOW CALCULATE LOSES FROM COATED SIDE

$$P_W \sim \int_0^{\Lambda} \int_0^a H_W^2(x, z) dx dz \quad P_N \sim \int_0^{\Lambda} \int_0^b H_N^2(y, z) dy dz$$

$$P_W = \frac{P_W}{P_W + P_N}$$

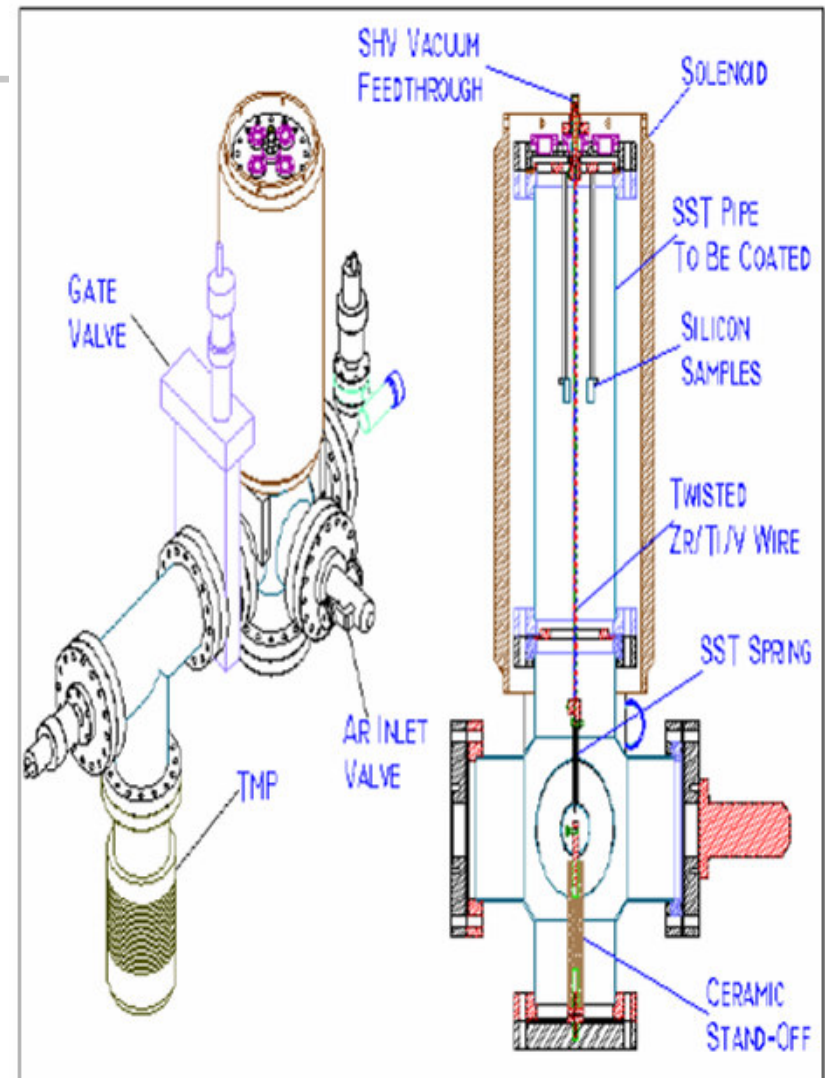
$$P_N = \frac{P_N}{P_W + P_N}$$



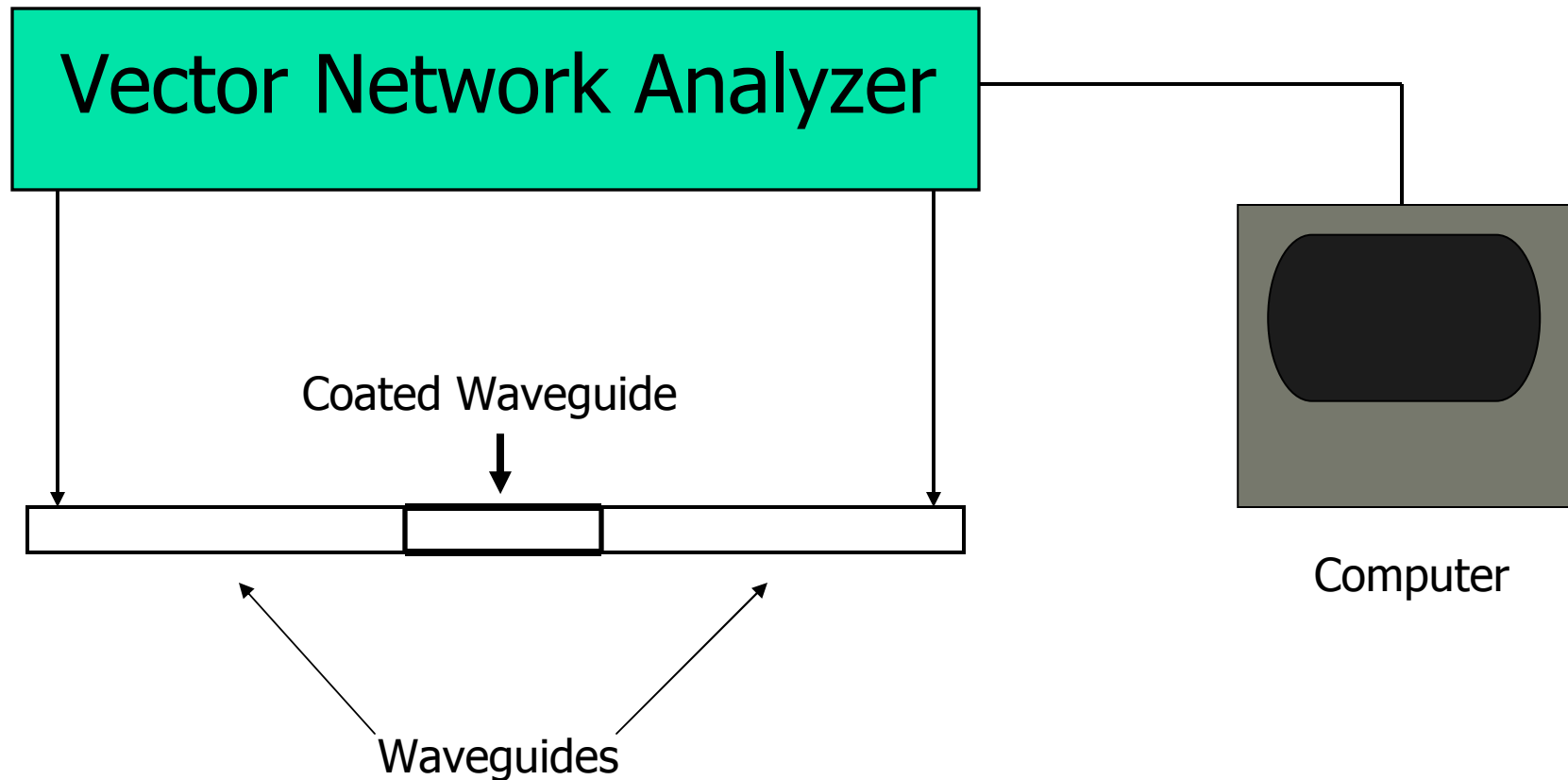
# Coating Apparatus

- DC MAGNETRON SPUTTERING
- NEGATIVE POTENTIAL APPLIED TO CATHODE
- AR/KR GAS SUBJECT TO FIELD IONIZATION
- ATOMS EJECTED FROM CATHODE FROM ENERGETIC ION BOMBARDMENT
- MAGNETIC FIELD TRAPS ELECTRONS TO INCREASE IONIZATION
- COATING RATE :

$$R_{\text{atom}} = \frac{N_{\text{atom}}}{A} = \frac{N_{\text{ion}} \cdot Y_{\text{sputter}}}{A} = \frac{I_{\text{ion}} \cdot Y_{\text{sputter}}}{2\pi aL \cdot q_e}$$



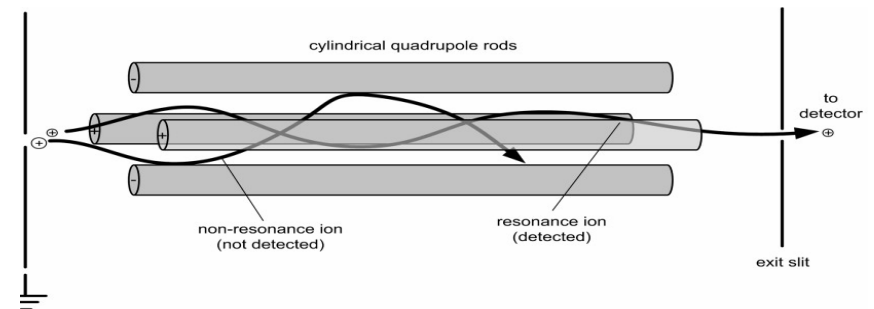
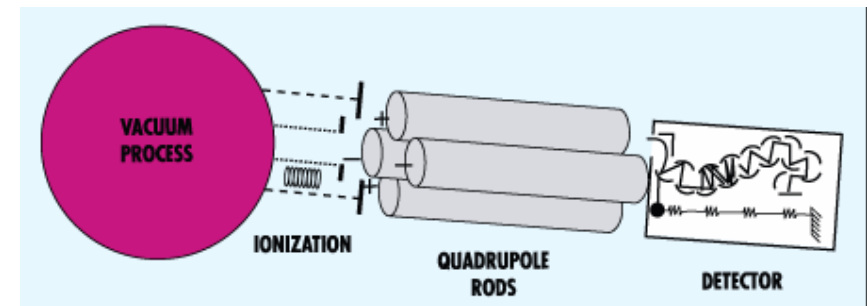
# Basic Setup for Measurements





# Additional project

- RESIDUAL GAS ANALYZERS (RGA) ARE IMPORTANT VACUUM TOOLS THAT ALERT WHEN A SYSTEM CONTAINS A LEAK AND ALSO WHAT GAS MOLECULES A VACUUM SYSTEM CONTAINS
- DETAILED CALIBRATION NECESSARY FOR ACCURATE RESULTS
- RGA WORK IN FOUR STEPS
  - ELECTRON IMPACT IONIZATION
  - ION OPTICS FOCUS BEAM
  - BEAM ENTERS MASS ANALYZER (RF QUADRUPOLE)
  - ION DETECTION THROUGH USE OF FARADAY CUP AND CHANNEL ELECTRON MULTIPLIER





# The Plan

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- LEARN TO USE CAD INVENTOR 11
- DESIGN WAVEGUIDE FOR THIN-FILM NEG COATING
- UNCOATED WAVEGUIDE FOR BASELINE MEASUREMENTS
- LEARN COATING TECHNIQUE
- COAT DESIGNED WAVEGUIDE
- TEST NEG WAVEGUIDE IN RF
- ANALYZE DATA FOR RF PROPERTIES OF NEG COATING
- CALIBRATE RGA FOR USE IN LEPP